INFORMATION DISCLOSURE CITATION *(Use several sheets if necessary)*	Docket Number (Optional) TWI-12410	Application Number NEW
	Applicant(s) Craig Uhrich et al.	
	Filing Date HEREWITH	Group Art Unit

U.S. PATENT DOCUMENTS

*Examiner Initial	Ref	Document Number	Date	Name	Class	Subclass	Filing Date
	AA	5,608,526	03/04/1997	Piwonka-Corle et al.	356	369	01/19/1995
	AB	5,877,859	03/02/1999	Aspnes et al.	356	364	07/24/1996

FOREIGN PATENT DOCUMENTS

	Ref	Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AC	WO 99/02970	01/21/1999	PCT	G01N	21/21		

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

	AD	D.E. Aspnes & A.A. Studna, "High Precision Scanning Ellipsometer," *Applied Optics*, Vol. 14, No. 1, January 1975, pp. 220-228.

Examiner	Date Considered 9/7/05

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INFORMATION DISCLOSURE CITATION *(Use several sheets if necessary)*	Docket Number (Optional) I-12410	Application Number 09/848,733
	Applicant(s) Craig Uhrich et al.	
	Filing Date May 3, 2001	Group Art Unit 2877

U.S. PATENT DOCUMENTS

*Examiner Initial	Ref	Document Number	Date	Name	Class	Subclass	Filing Date
DP	BA	3,486,805	12/30/1969	Kobayashi	350	2	02/09/1966
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FOREIGN PATENT DOCUMENTS

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							Yes	No

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(Including Author, Title, Date, Pertinent Pages, Etc.)

Examiner	Date Considered 9/7/09

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